

LESKER U AND 4D LABS PRESENT:

VACUUM TECHNOLOGY TRAINING:

ULTRA-HIGH VACUUM SCIENCE & SYSTEM CHARACTERIZATION



This Free Workshop will review
Vacuum Science Fundamentals
and apply them to
Physical Vapour Deposition of Thin Films
and **Thin Film Growth Models**

TOPICS PRESENTED INCLUDE:

9:00 am – 12:00 pm:

Introduction to Vacuum Science & System Design

Resources for Physical Vapour Deposition

Thermal and Electron Beam Evaporation

DC, Pulsed DC, RF, and HiPIMS Sputtering

12:00 pm—1:00 pm: Lunch Break

1:00 pm to 4:00 pm:

Special Considerations for UHV

Characterizing Vacuum Systems

Troubleshooting Sputtering Processes

Introduction to Atomic Layer Deposition

Thin Film Models and Structure Zone Diagrams

Register early—seating is limited. Tickets available at:

https://Lesker_U_Vacuum_Tech_Training.eventbrite.ca



Date

Oct 22, 2026

Location

SSC 9051

Time

9:00 am - 4:00 PM

FREE ADMISSION

Lunch/Refreshments Provided

Kurt J. Lesker
Company

SFU

4D LABS